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PATENT

2877

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IN THE UNITED STATES

PATENT AND TRADEMARK OFFICE

APPLICANT(S): Steven W. Meeks et al.
APPLICATION NO.: 09/347,622 ✓
FILING DATE: July 2, 1999
TITLE: System for Simultaneously Measuring Thin Film Layers Thickness,
Reflectivity, Roughness, Surface Profile and Magnetic Pattern
EXAMINER: T. Nguyen
GROUP ART UNIT: 2877
ATTY. DKT. NO.: 20830-04304

CERTIFICATE OF MAILING

I hereby certify that this correspondence is being deposited with the United States Postal Service as first class mail in an envelope addressed to: Commissioner For Patents, P.O. Box 1450, Alexandria, VA 22313-1450, on the date shown below:

Dated: August 4, 2003

By:

Nathan S. Huynh, Reg. No.: 53,052

COMMISSIONER FOR PATENTS
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STATUS REQUEST

SIR:

Our file for the subject application reveals that there has been no action on this application since the filing of the Information Disclosure Statement on July 14, 2003.

Please inform the undersigned, at the below stated address, of the status of this application.

Respectfully submitted,
Steven W. Meeks et al..

Dated: August 4, 2003

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